p-BaSi₂/n-Si heterojunction solar cells on Si(001) with conversion efficiency approaching 10%: comparison with Si(111)

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B-doped p-BaSi₂ epitaxial layers with a hole concentration of 1.1×10^{18} cm⁻³ were grown on n-Si(001) using molecular beam epitaxy to fabricate p-BaSi₂/n-Si solar cells. The thickness (*d*) of the p-BaSi₂ layer was varied from 20 to 60 nm to investigate its effect on solar cell performance. The conversion efficiency under AM1.5 illumination increased with *d* reaching a maximum of 9.8% at *d* = 40 nm, which is almost the same as the highest efficiency (9.9%) for p-BaSi₂/n-Si solar cells on Si(111). This work indicated that Si(001) substrates show promise for use in BaSi₂ solar cells.

A wide variety of materials have gained increasing attention for use in solar cells, including cadmium telluride, chalcopyrite, kesterite, and perovskite. These materials have allowed high conversion efficiencies (η) in low-cost solar cells. However, many of these materials contain rare and/or toxic elements. Therefore, finding effective absorber materials that are environmentally friendly is of great importance. Semiconducting orthorhombic barium disilicide (BaSi₂), composed of abundant elements, shows great potential as a solar cell material¹ as it has a suitable band gap of 1.3 eV^{2,3} and a large absorption coefficient (α) of 3 × 10^4 cm⁻¹ at 1.5 eV,³⁻⁵ which is almost 40 times larger than that of crystalline silicon. A high η of over 25% is expected for a 2-µm-thick BaSi₂ homojunction solar cell.⁶ In addition, alternative BaSi₂ containing solar cells have been proposed, such as BaSi₂ nanowires, back-contacted BaSi₂ solar cells and BaSi₂/perovskite stacked layers.⁷⁻⁹ BaSi₂ can be grown epitaxially on a Si substrate^{10,11} and its band gap can be increased by adding other elements such as Sr and C.^{12,13} Thereby, BaSi₂ is a material of choice for targeting $\eta > 30\%$ in a Si-based tandem structure solar cell. As a first step, we chose to fabricate p-BaSi₂/n-Si heterojunction diodes on a flat n-Si(111) substrate, and achieved η values of 9.9%.¹⁴ This is the highest η ever recorded for solar cells fabricated with semiconducting silicides. We have found that η was improved significantly by capping the p-BaSi₂ surface with an approximately 3-nm-thick amorphous Si (a-Si) layer.¹⁵ These findings led to the recent success of BaSi₂ homojunction solar cells.¹⁶ BaSi₂ containing solar cells are usually fabricated on Si(111) surfaces, even though the production of Si(001) substrates is far more abundant. We have used Si(111) substrates because BaSi₂ epitaxial films on Si(111) have exhibited a large minority-carrier lifetime (~10 µs), a large minority-carrier diffusion length (L~10 µm), and inactive grain boundaries.¹⁷⁻²⁰ In addition, the lattice mismatch is as large as approximately 1% for BaSi₂ on Si(111), which is much smaller than 12% for BaSi₂ on Si(001).¹¹ However, recent achievements in BaSi₂ on Si(001) such as large photoresponsivity and p-BaSi₂/n-Si solar cells have renewed interest in BaSi₂ on Si(001).²¹⁻²³ In this work, to explore the potential of Si(001) substrates for p-BaSi₂/n-Si heterojunction and BaSi₂ homojunction solar cells, we fabricated p-BaSi₂ films on Si(001) substrates with thicknesses (*d*) ranging from 20 to 60 nm by molecular beam epitaxy (MBE). The hole concentration (*p*) was fixed at 1.1×10^{18} cm⁻³. An η of 9.8%, which was comparable to the highest η obtained when fabricated on Si(111), was obtained at *d* = 40 nm under AM1.5 illumination. Moreover, both *b* and *c*-axis of the BaSi₂ films were under compressive strain, which was confirmed using Raman spectroscopy.

Samples were prepared using an ion-pumped MBE (R-DEC) system with a base pressure of less than 10^{-8} Pa, equipped with an electron-beam evaporation source for Si and standard Knudsen cells (K-cells) for Ba and B. These sample preparation procedures have been reported previously.²⁴ The p-type BaSi₂ epitaxial films (d = 20, 30, 35, 40, 50, and 60) were grown on n-Si(001) substrates (resistivity $\rho = 1-10 \ \Omega cm$) and were named samples A-F, respectively. The crucible temperature of the B K-cell ($T_{\rm B}$) was set at 1170 °C to satisfy p = 1.1 $\times 10^{18}$ cm⁻³. Subsequently, a 3-nm-thick a-Si capping layer was deposited on the BaSi₂ layers at 180 °C to prevent oxidation of the BaSi₂ films.²⁵ The crystalline quality of films was characterized using reflection high-energy electron diffraction (RHEED) and X-ray diffraction (XRD; RIGAKU, Smart Lab) using Cu Ka radiation. The out-of-plane and in-plane XRD measurements gave the a, b, and c-axis lattice constants (a, b, and c) using the Nelson-Riely relationship.²⁶ A 440-nm-thick BaSi₂ film was used as a reference. Raman spectra were measured with a laser Raman spectrometer (JEOL, NRS-5100) with a frequency doubled Nd:YAG laser (532 nm). Surface morphologies were investigated using atomic force microscopy (AFM; Shimadzu SPM-9600). For optical characterization, an 80-nm-thick indium-tin-oxide (ITO) electrode (diameter = 1 mm) was sputtered on the front side and a 150nm-thick Al electrode was sputtered on the entire back side. The current density versus voltage (J-V) characteristics under standard AM1.5 illumination and the photoresponse spectra were measured using a xenon lamp with a 25-cm-focal-length single monochromator (Bunko Keiki, SM-1700A and RU-60N). All measurements were performed at ambient temperature using a mask with 1-mm-diameter holes, and the results were compared with those reported for devices fabricated on Si(111) substrates.²⁷

The growth of the *a*-axis orientated p-BaSi₂ epitaxial films was confirmed for all samples using RHEED and XRD patterns. The J-V curves under AM1.5 illumination and external quantum efficiency (EQE) spectra for samples A-F are shown in Figs. 1(a) and 1(b), respectively. Solar cell behavior was observed for the devices fabricated on the Si(001) substrates in spite of the large lattice mismatch (~12%). The valence and conduction band offsets at the BaSi₂/Si interface, which is approximately 0.6 and 0.8 eV, respectively, promote the separation of photogenerated electrons and holes, as well as those in n-Si.²⁴ Equivalent data for p-BaSi₂/n-Si solar cells fabricated on Si(111) is shown in Figs. 1(c) and 1(d).²⁷ The solar cell performance of the devices fabricated on the Si(001) substrates changed depending on the value of d, with the largest η (9.8%) being obtained for sample D (d = 40 nm). This device exhibited a short-circuit current density (J_{SC}) of 37.0 mA/cm², an open-circuit voltage (V_{OC}) of 0.44 V, and a fill factor (FF) of 59.7%. The J-V curves (Fig. 1(a)) showed that the η improved for larger values of d initially, and then decreased because of a significant decrease in the J_{SC} . In addition, the V_{OC} almost saturated when d > 30 nm. The optimum d value for the p-BaSi₂/n-Si(111) solar cell was 20 nm (Fig. 1(c)).²⁷ The contribution of photogenerated carriers in the p- $BaSi_2$ layer decreased, especially in the short wavelength range, with increasing values of d (Figs. 1(b) and 1(d)). This indicated that it was difficult for the photogenerated minority carriers (electrons) in the p-BaSi₂ layer to reach the junction before recombination as d increased. This is attributed to a reduced L in the p-BaSi₂ films. Figure 1(e) presents the EQE spectra of p-BaSi₂/n-Si samples at d = 50 nm. Because α reaches 4×10^5 cm⁻¹ at a wavelength of 500 nm in BaSi₂,³ a large fraction of photons (>85%) at this wavelength are absorbed as they travel as far as 50 nm $(1/\alpha \times 2 = 50 \text{ nm})$ through the p-BaSi₂ layer. The *EQE* values for sample on Si(001) are smaller than those on Si(111) especially in the short wavelength range, meaning that the L of the p-BaSi₂ on Si(001) is smaller than that on Si(111). We have already measured L values of undoped BaSi₂ films on Si(111) and Si(001) by an electron-beam-induced-current (EBIC) technique, and they are 10 and 1.5 μ m, respectively.²⁸ This difference in *L* comes from inactive grain boundaries of BaSi₂ on Si(111).²⁹ Although we have not evaluated *L* values of p-BaSi₂ films by EBIC, it is reasonable to consider that they are smaller for p-BaSi₂ on Si(001) than those on Si(111). Figure 1(f) shows the schematics of the band alignment of the diode simulated by automat for simulation of heterostructures (AFORS-HET).³⁰ The band bending occurs in the region close to the interface under illumination, marked by broken circles, and acts to disturb the transport of photogenerated electrons in the p-BaSi₂ to the n-Si region and photogenerated holes in the n-Si to the p-BaSi₂ region. This is caused by a small built-in potential of the diode (~ 0.2 V) because of a small electron affinity of BaSi₂ (3.2 eV).³¹ Since such a band bending may limit the η of a p-BaSi₂/n-Si solar cell, we need to work on BaSi₂ homojunction solar cells to achieve much a higher η .

To accurately determine the reverse-bias saturation current density (J_0), shunt resistance (R_{SH}), and series resistance (R_S), we adopted a technique described by J. R. Sites and P. H. Mauk³² and summarized in Fig. 2. Using the photodiode equation, the above parameters can be described using Eq. (1):

$$\frac{dV}{dJ} = SR_{\rm S} + \frac{\gamma k_{\rm B}T}{q} \left[\frac{1 - (SR_{\rm SH})^{-1} dV/dJ}{J + J_{SC} - (SR_{\rm SH})^{-1}V} \right].$$
 (1)

Here, *S* is the device area, γ is the ideality factor of the diode, $k_{\rm B}$ is the Boltzmann constant, *T* is the absolute temperature, and *q* is the elemental charge. The J_0 decreased from 0.20 mA/cm² at d = 20 nm to 9.04×10^{-6} mA/cm² at d = 40 nm, which was comparable to the J_0 obtained for the p-BaSi₂/n-Si solar cell fabricated on Si(111) ($J_0 = 1.39 \times 10^{-5}$ mA/cm²) with the highest η .²⁷ This result highlights the promise of BaSi₂ solar cells fabricated on Si(001) substrates. The decrease in the η at low values of d (20 and 30 nm, Fig. 2) was primarily caused by small *FF*s because of large $R_{\rm S}$ and small $R_{\rm SH}$. To understand this decreased η at low d we examined the surface morphologies (5 µm × 5 µm) and cross-sectional profiles of p-BaSi₂ layers using AFM

for samples with d = 20, 40, and 60 nm, as shown in Fig. 3. These morphologies were examined before the deposition of the ITO surface electrode. The sample with d = 20 nm exhibited grain boundaries with gaps with depths of approximately 14 nm (Fig. 4(a)), showing that the entire Si surface was not covered by the film. The small R_{SH} calculated for this film likely originated from current leakage paths introduced as a consequence of direct contact between the ITO and the n-Si(001) substrate. At d = 40 and 60 nm, the n-Si(001) substrate was entirely covered with p-BaSi₂, resulting in the smaller J_0 and larger R_{SH} values. These results clearly demonstrated that contact of ITO and p-BaSi₂ and contact of p-BaSi₂ and n-Si have significant impacts on the values of R_{SH} and J_0 . Conversely, a d of 20 nm was sufficient to cover the entire n-Si(111) surface, while d = 10 nm was not enough.²⁷

The strains $(\Delta a/a, \Delta b/b, \text{ and } \Delta c/c)$, normalized using those of a reference sample with d = 440 nm, as functions of d on the Si(001) substrate are shown in Fig. 4(a). The equivalent graphs obtained on Si(111) substrates are presented in Fig. 4(b).³³ Surprisingly, the values of $\Delta a/a$, $\Delta b/b$, and $\Delta c/c$ were all negative when d was equal to or smaller than 60 nm. Their magnitude decreased monotonically and approached 0, which indicated that the BaSi₂ films were under compressive strain. In contrast, $\Delta a/a$ on the Si(111) substrate was positive and the dependence of the strain on d was more complicated (Fig. 4(b)). It is plausible that these differences in strain caused the different thicknesses of the p-BaSi₂ layer required to cover the entire n-Si surface when comparing Si(111) and Si(001) substrates. Raman spectra of the p-BaSi₂ films on the Si(001) substrate with different d values are shown in Fig. 4(c). Five Raman peaks were observed at wavenumbers below 500 $cm^{-1},^{34}$ denoted by $F_g,\,E_g,\,E_g+F_g,\,F_g,$ and $A_g,$ in addition to an intense peak (520.2 cm⁻¹) caused by the transverse optical phonon of Si (Si_{TO}) from the substrate. The Raman peaks Fg, Eg, and Ag originated from tetrahedral Si with Th symmetry in the lattice of $BaSi_2$.³⁵ The peak positions in the Raman spectra as functions of d are shown in Fig. 4(d). As d increased, all peaks shifted to a smaller wavenumbers, which indicated that the films were under compressive stress in the in-plane direction.³⁶ This compressive stress was consistent with the strains ($\Delta b/b < 0$ and $\Delta c/c < 0$) when considering the elastic stiffness constants of BaSi₂ using the elastic stress-strain relationship described by M. Grundmann.³⁷ As the Si *p* state appears dominant in the valence band maximum of BaSi₂ in both theory^{4,5,38} and experiment,³⁹ it is possible that the stress introduced in the tetrahedral Si within the lattice modified the band structure of BaSi₂, leading to differences in its optical properties. Although further studies are required to verify the relationship between the induced stress and optical properties of BaSi₂, this work shows that Si(001) substrates are useful for BaSi₂ solar cells.

In summary, we fabricated B-doped p-BaSi₂/n-Si heterojunction solar cells on Si(001) substrates with different BaSi₂ layer thicknesses. We then examined the influence of the BaSi₂ thickness on the solar cells properties. The p-BaSi₂ films were found to be under compressive strain as well as compressive stress in the in-plane direction when d < 60 nm. The η reached a maximum value of 9.8% with a J_{SC} of 37.0 mA/cm², a V_{OC} of 0.44V, and a *FF* of 59.7%. These values were comparable to those obtained for devices fabricated on Si(111), indicating that Si(001) substrates can also be used for BaSi₂ solar cells.

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Figure captions

Fig. 1. *J-V* curves and *EQE* spectra of the p-BaSi₂/n-Si solar cells on Si(001) substrates ((a) and (b), respectively) and on Si(111) substrates ((c) and (d), respectively). (e) *EQE* spectra of the p-BaSi₂/n-Si solar cells on Si(001) and Si(111) substrates at d = 50 nm in (b) and (d). (f) Schematics of calculated band alignments of a p-BaSi₂ (50 nm)/n-Si solar cell during short-circuit condition (left) and open-circuit condition (right) by AFORS-HET. *E*_C and *E*_V denote the conduction-band minimum and the valence-band maximum, respectively.

Fig. 2. Solar cell parameters (η , V_{OC} , J_{SC} , FF, R_S , R_{SH} , and J_0) of p-BaSi₂/n-Si solar cells formed on Si(001) and on Si(111)²⁷ substrates determined through calculations using Eq. (1).

Fig. 3. AFM images (5 μ m \times 5 μ m) and cross-sectional profiles (along the white line) of p-BaSi₂ layers from samples (a) A, (b) D, and (c) F.

Fig. 4. Normalized strains ($\Delta a/a$, $\Delta b/b$, and $\Delta c/c$) as functions of p-BaSi₂ thickness grown on (a) Si(001) and (b) Si(111).³³ (c) Raman spectra of p-BaSi₂ films on n-Si(001). (d) Raman peak positions as functions of thickness for the p-BaSi₂ films.



Fig. 1



Fig. 2



Fig. 3



Fig. 4